Manufacturing Diagnosis and Control: A Task-Specific Approach

The Theory and Application of Diagnostic and Control Expert System Based on Plant Model

Integrated Problem Solving for the Diagnosis of Interacting Process Malfunctions

A Neural Network Model for Diagnostic Problem Solving

Process Control System for VLSI Fabrication

Development and Application of Equipment-Specific Process Models for Semiconductor Manufacturing

Continuous Equipment Diagnosis Using Evidence Integration - An LPCVD Application

Equipment/Instrument Diagnosis with Continuous and Discrete Causal Relationships

Intelligent Control of Semiconductor Manufacturing Processes

A Machine Learning Approach to Diagnosis and Control with Applications in Semiconductor Manufacturing

Table of Contents provided by Blackwell's Book Services and R.R. Bowker. Used with permission.